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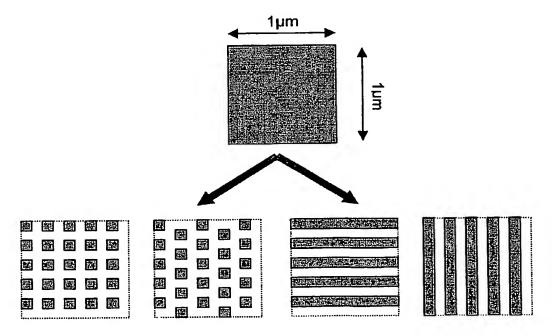
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(54) Title: OVERLAY METROLOGY MARK



(57) Abstract: An overlay metrology mark for determining the relative position between two or more layers of an integrated circuit structure comprising a first mark portion associated with and in particular developed on a first layer and a second mark portion associated with and in particular developed on the surface of a second layer, wherein each mark portion comprises a single two dimensional generally orthogonal array of individual test structures. A method of marking and a method of determining overlay error are also described.

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C. DOCUMENTS CONSIDERED TO BE RELEVANT	
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Further documents are listed in the continuation of t	DOX C. Patent family members are listed in annex.
Special categories of cited documents: 'A' document defining the general state of the art which is considered to be of particular relevance 'E' earlier document but published on or after the internatifiling date 'L' document which may throw doubts on priority claim(s) which is cited to establish the publication date of anoticitation or other special reason (as specified) 'O' document referring to an oral disclosure, use, exhibition other means 'P' document published prior to the international filing date later than the priority date claimed	invention "X" document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone ther "Y" document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such document is combined with one or more other such documents, such combination being obvious to a person skilled in the erf
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